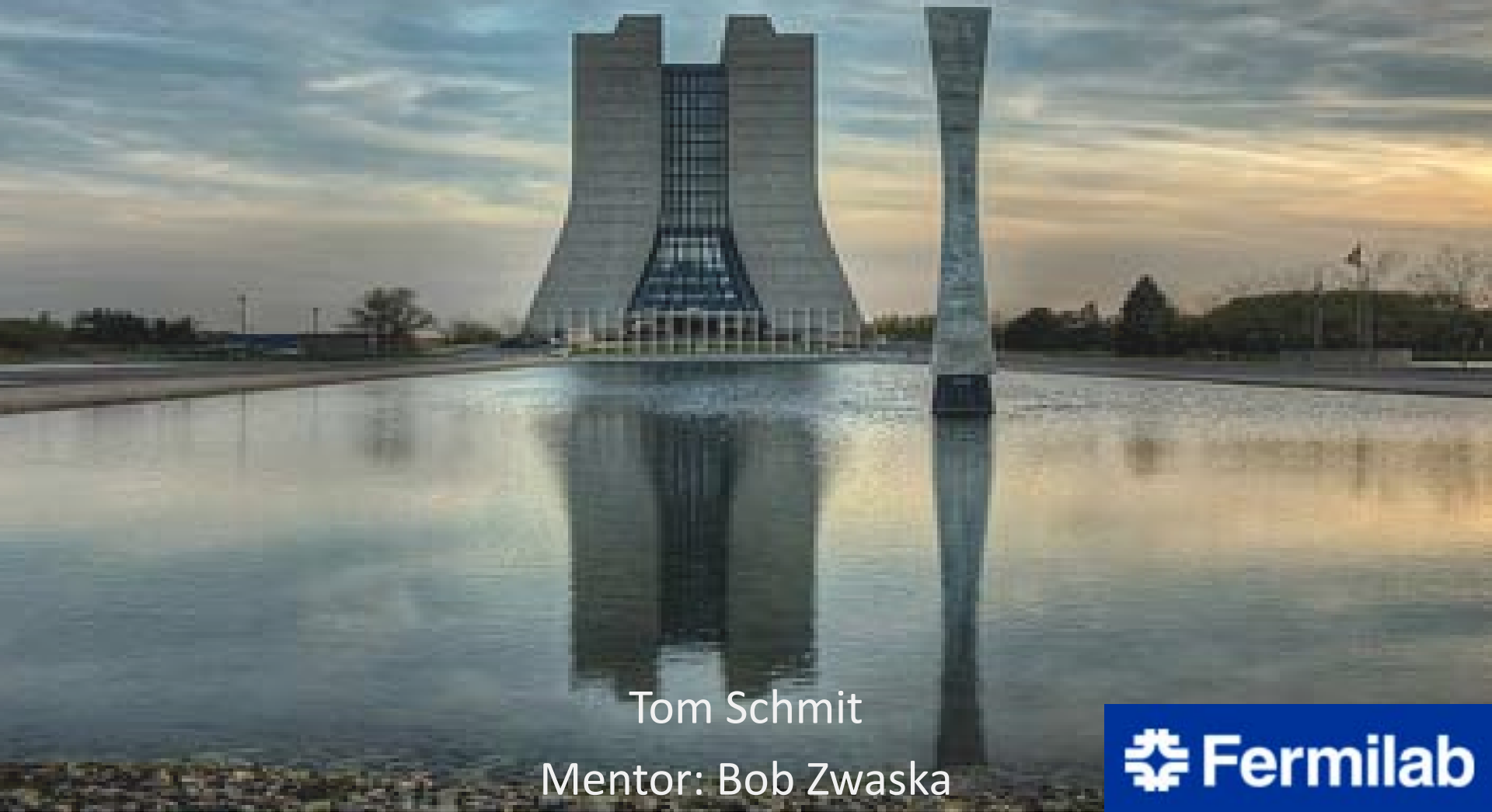


The Electron Cloud And Secondary Electron Yield



Tom Schmit

Mentor: Bob Zwaska

The Electron Cloud

- Fermilab and the intensity frontier
 - Accelerators are approaching a new regime in intensity
 - Many difficulties are associated with increased intensity
- Increased intensity results in electron cloud instabilities
 - Very hard problem to solve analytically
 - Not well understood

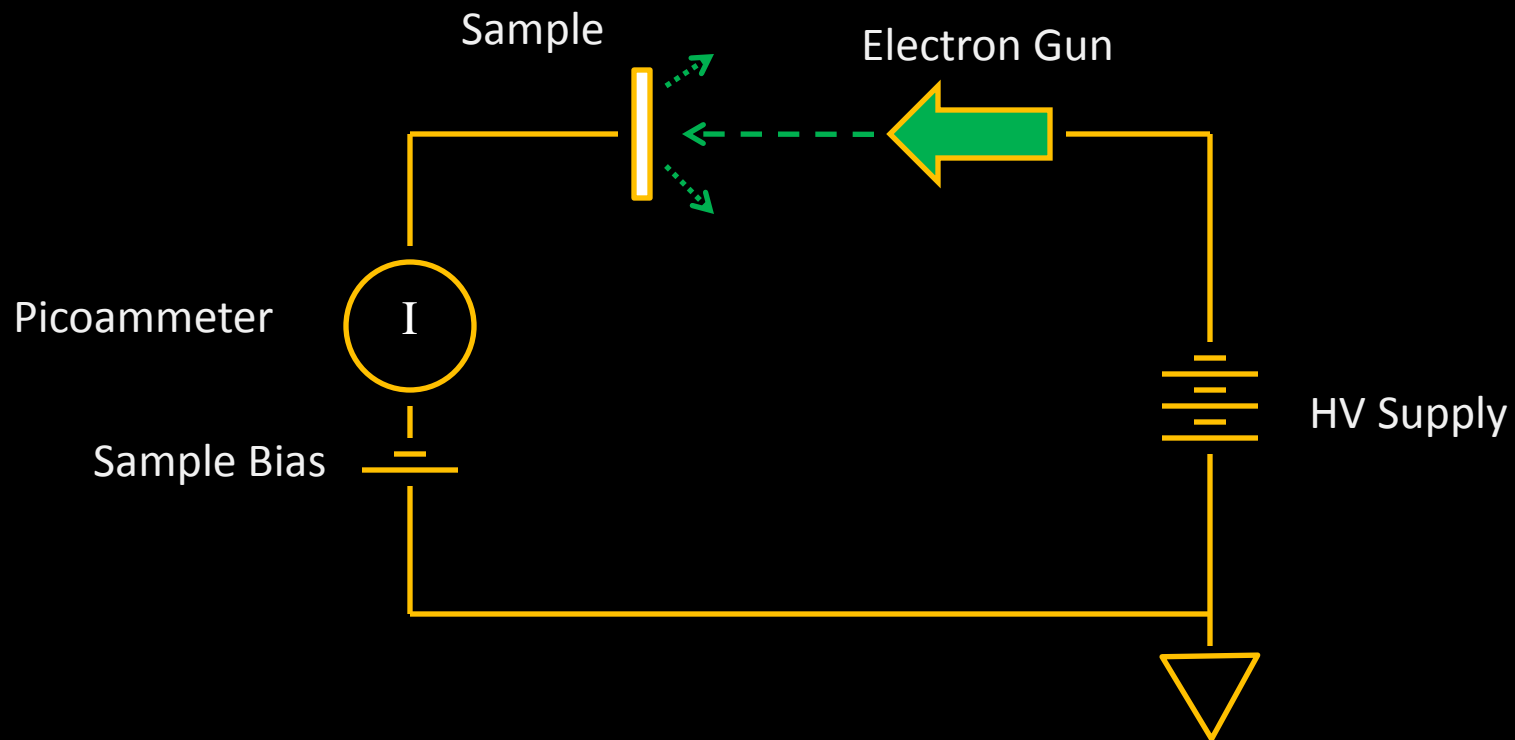
The Electron Cloud

- A secondary effect of accelerating particles
 - Primary electrons collide with beam pipe and components and generate secondary electrons
 - In proton/antiproton accelerators, primary electrons are formed mostly from residual gas ionization
 - In electron/positron machines, primary electrons are generated by the photoelectric effect
 - Secondary electron yield greater than unity for most materials => AMPLIFICATION!

Secondary Electron Yield

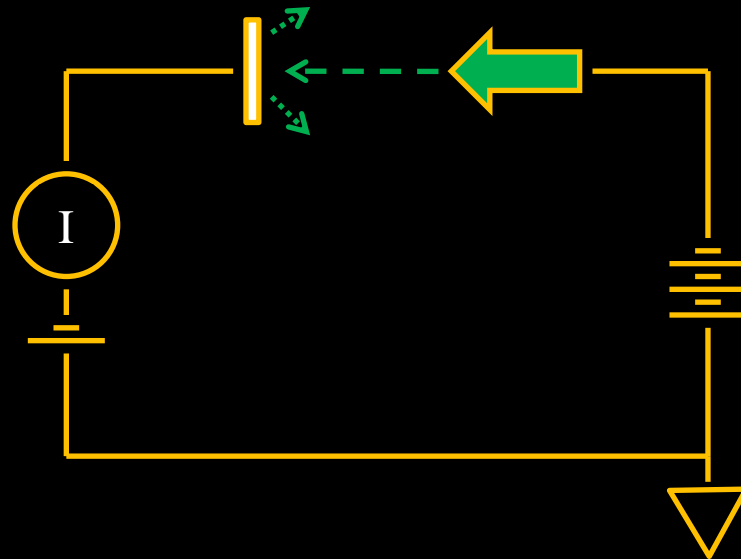
- Combat electron cloud formation by reducing secondary electron yield
- Commission a test stand to examine different materials for use in a beam line
 - Must be vacuum compatible
 - Durable
 - Have a low SEY

The Setup



SEY Measurement Technique

- Bias the sample to +500 volts and measure beam current
- Bias sample to -50 volts and measure current
- SEY current is the difference between the -50 V bias reading and the +500 V bias reading
- SEY is then given as the ratio of SEY current to beam current

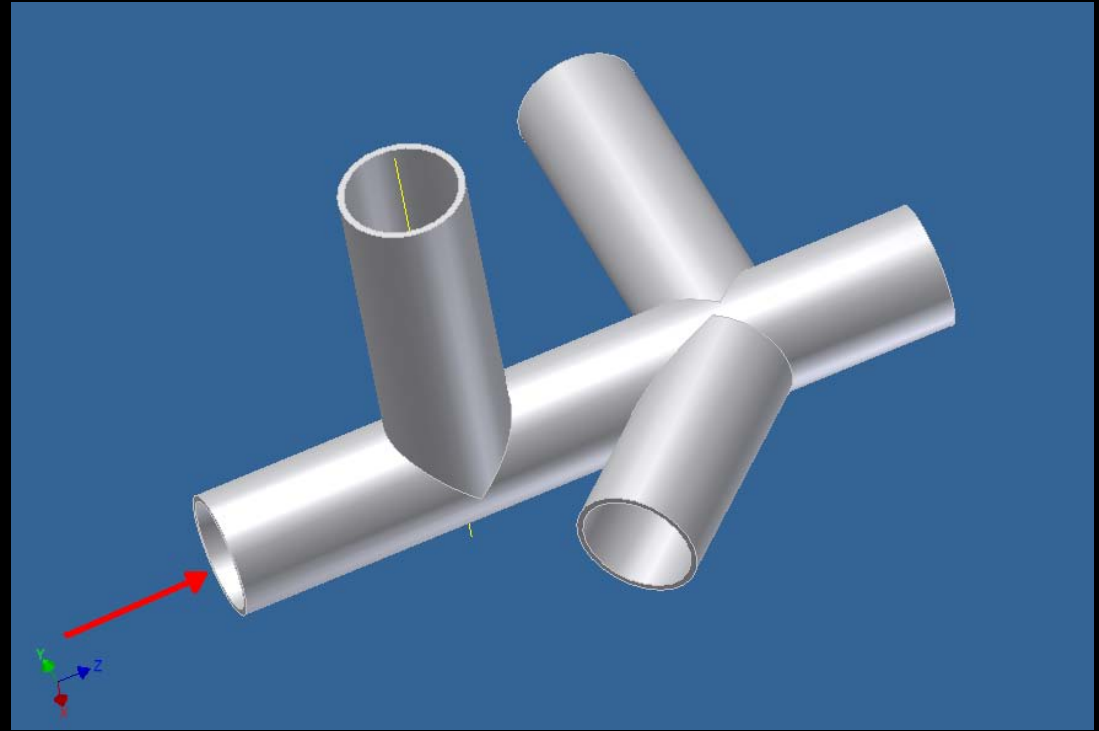


In Practice

- Sample is stationary and electrically isolated (mounted to SHV feedthrough)

- Pumped with Varian TPS-Compact pumping station (turbo pump backed with oil-less scroll pump)

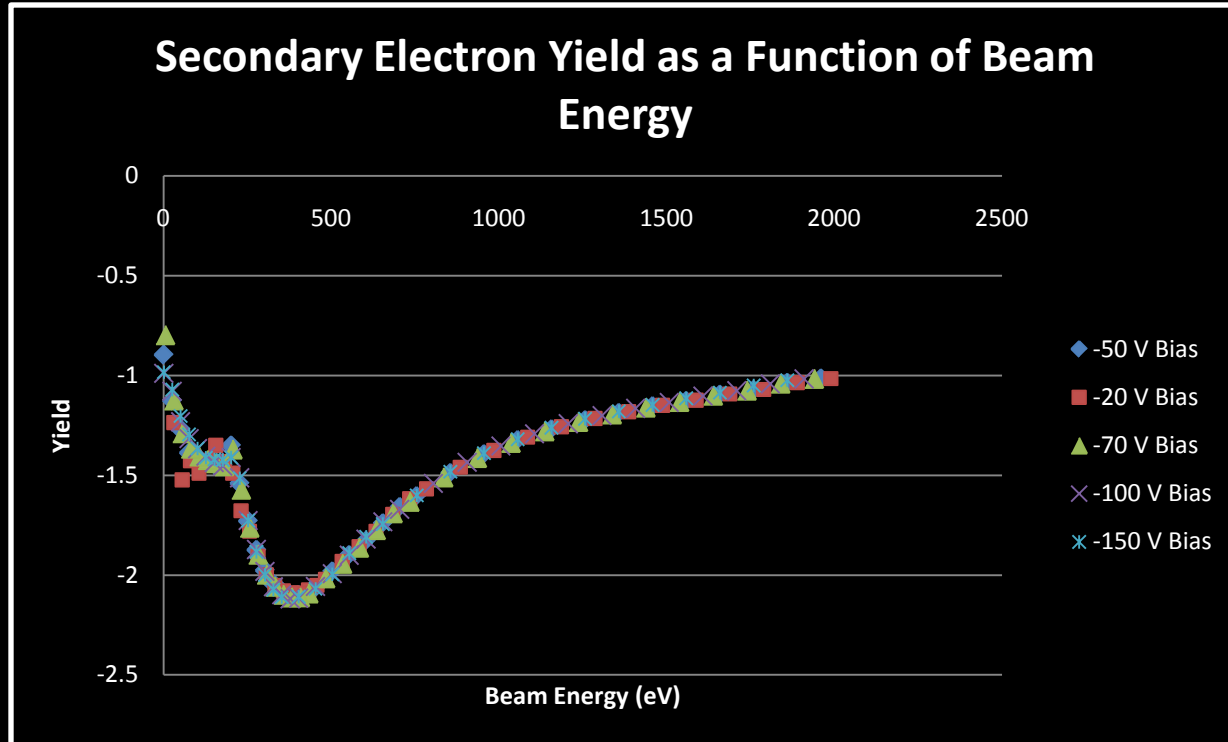
- Inverted Magnetron Pirani vacuum gauge



-> Electron beam indicated by red arrow

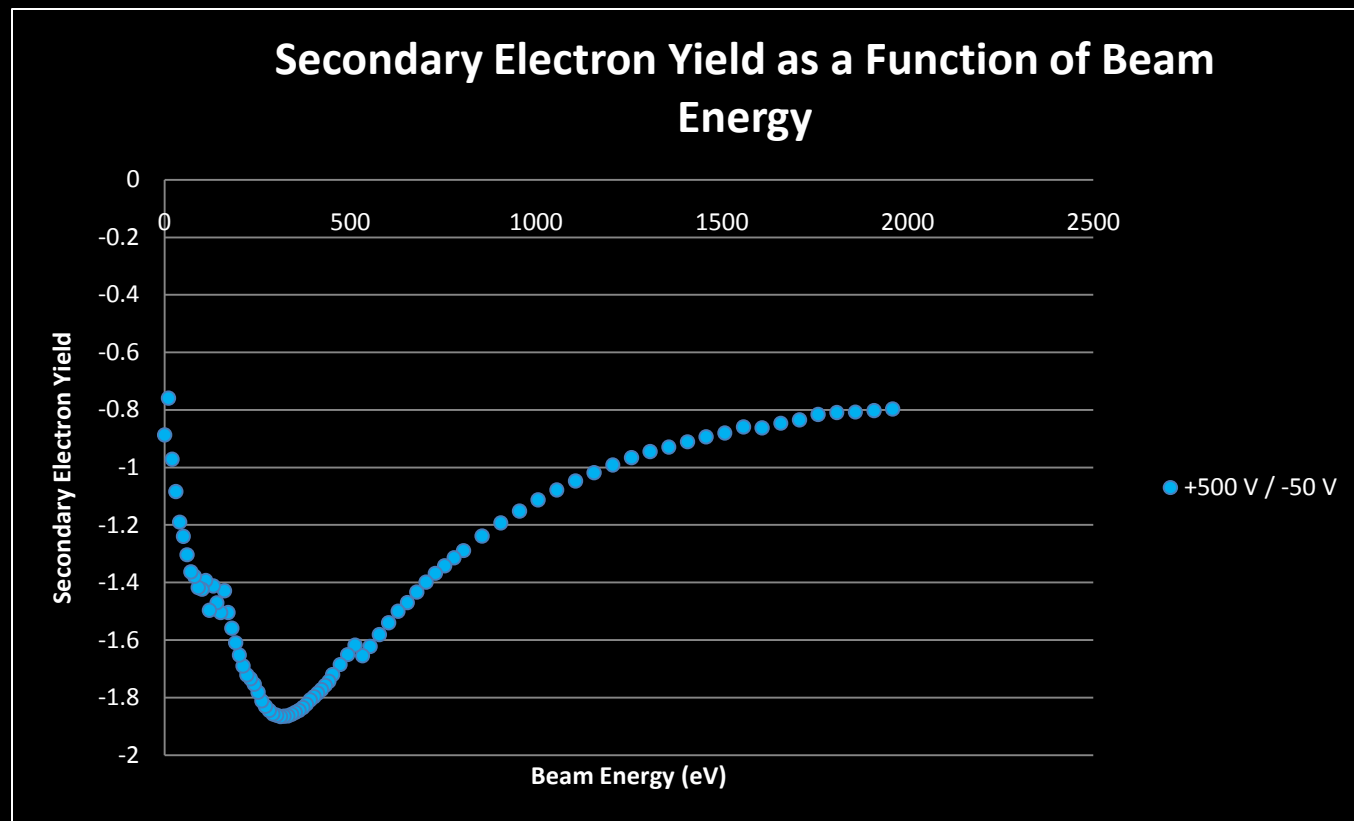
SEY Measurement Technique

- Why -50 volts?
 - Convention suggests -20 volts



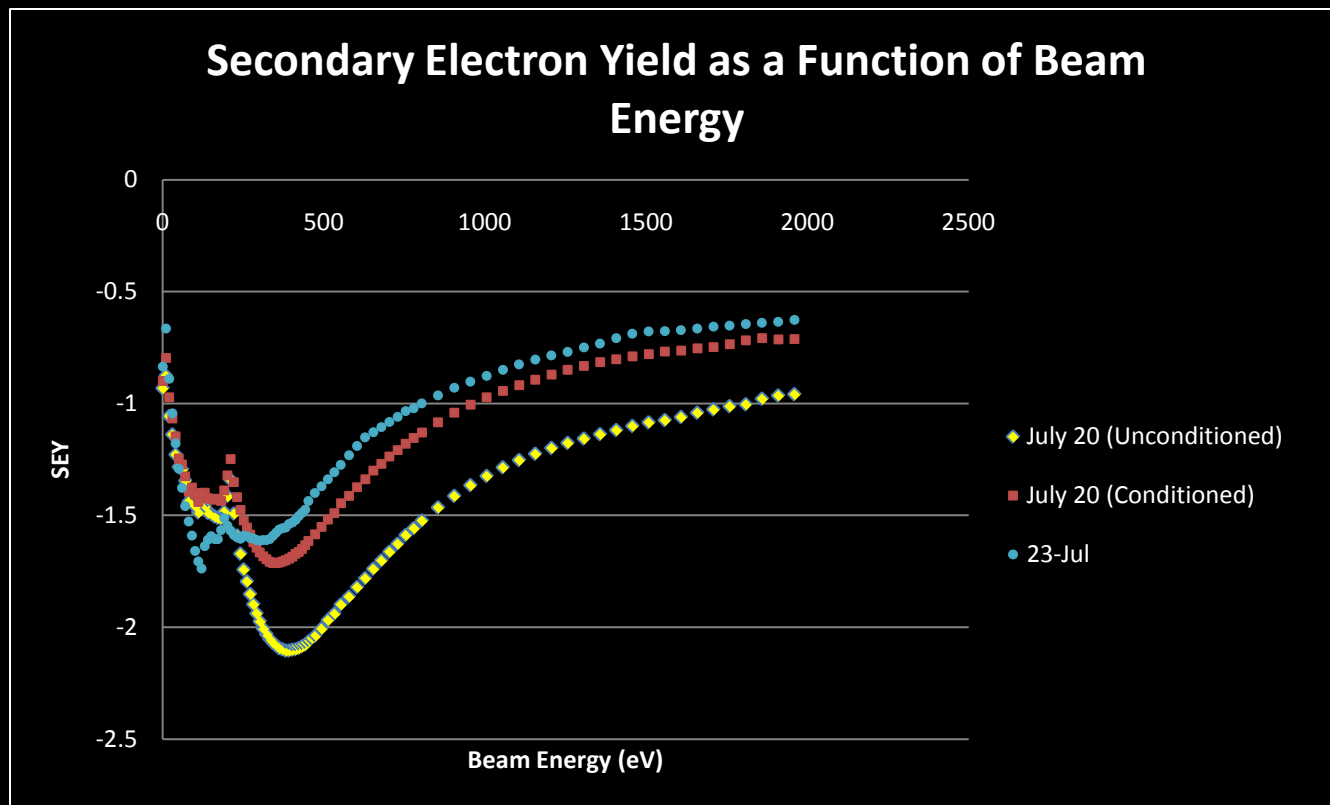
Initial Results

- Copper sample
- Qualitatively good data



Initial Results

- Copper sample
- Proof of conditioning



Refining the Technique

- Stray magnetic fields from gauge and ion pump had an unknown effect on low energy beams
 - *Mu-metal shielding*
- SEY measurements appeared to be sensitive to gun parameters
 - Spot size changes as parameters change
 - Measurement drift due to self-conditioning
 - *Perform beam studies*
 - *Speed up measurements by automating process with LabView*
- SEY current from residual gas ionization (i.e. not all of the measured current was necessarily from sample)
 - *Improve vacuum*

Refinements

- Shielded gauge using AD-MU-80; a high nickel alloy with a very large μ
 - Magnetic field reduced to a maximum of 3 gauss outside the chamber and ~ 1 gauss in the chamber
- Installed an ion pump
 - Vacuum improved to $4.1 \text{ E } -7$
 - > Dirty sample (typical monolayer formation time ~ 25 seconds according to *Building Scientific Apparatus* by Moore, Davis and Coplan)
- Performed basic beam study; spot size measured through beam extinction technique

MYSTERY MAGNETICS

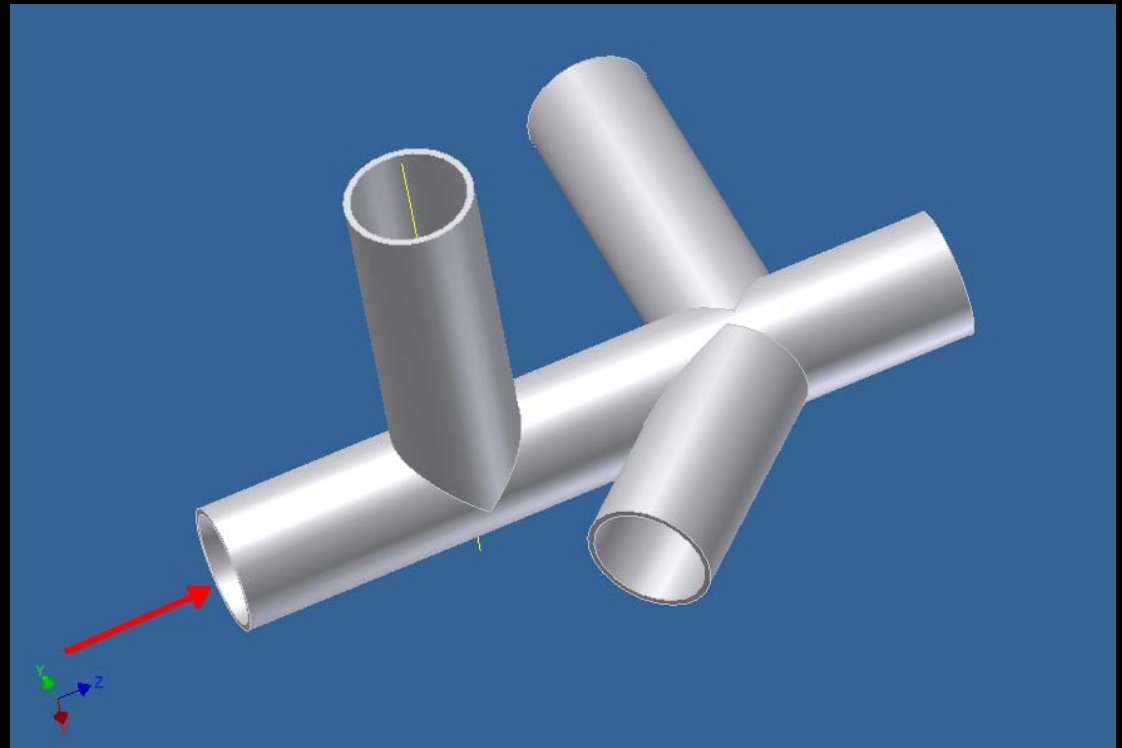
- Vacuum gauge produces a field of roughly 30 gauss at the KF flange
- After removal, 8-9 gauss still measured inside the chamber!
- Supports for the test stand were magnetic; fields on the order of 42 gauss!
- SOLUTION: Build degausser using a half torroid ferrite and a variac.

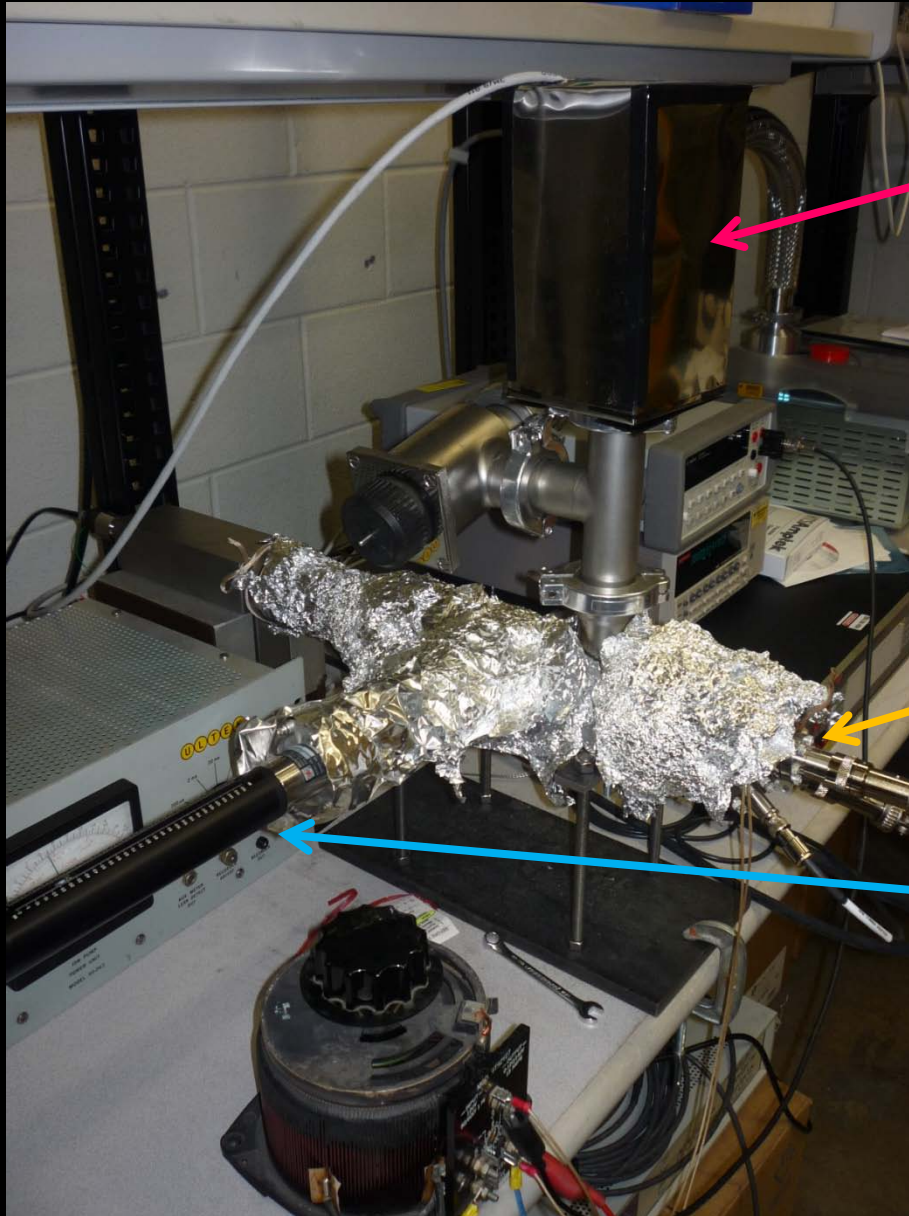
Degaussing a Wrench



Improved Test Stand

- Sample electrically isolated and stationary
- Aperture mounted on mechanical feedthrough for extinction measurements
- Ion pump installed





Mu-Metal shielding
for gauge

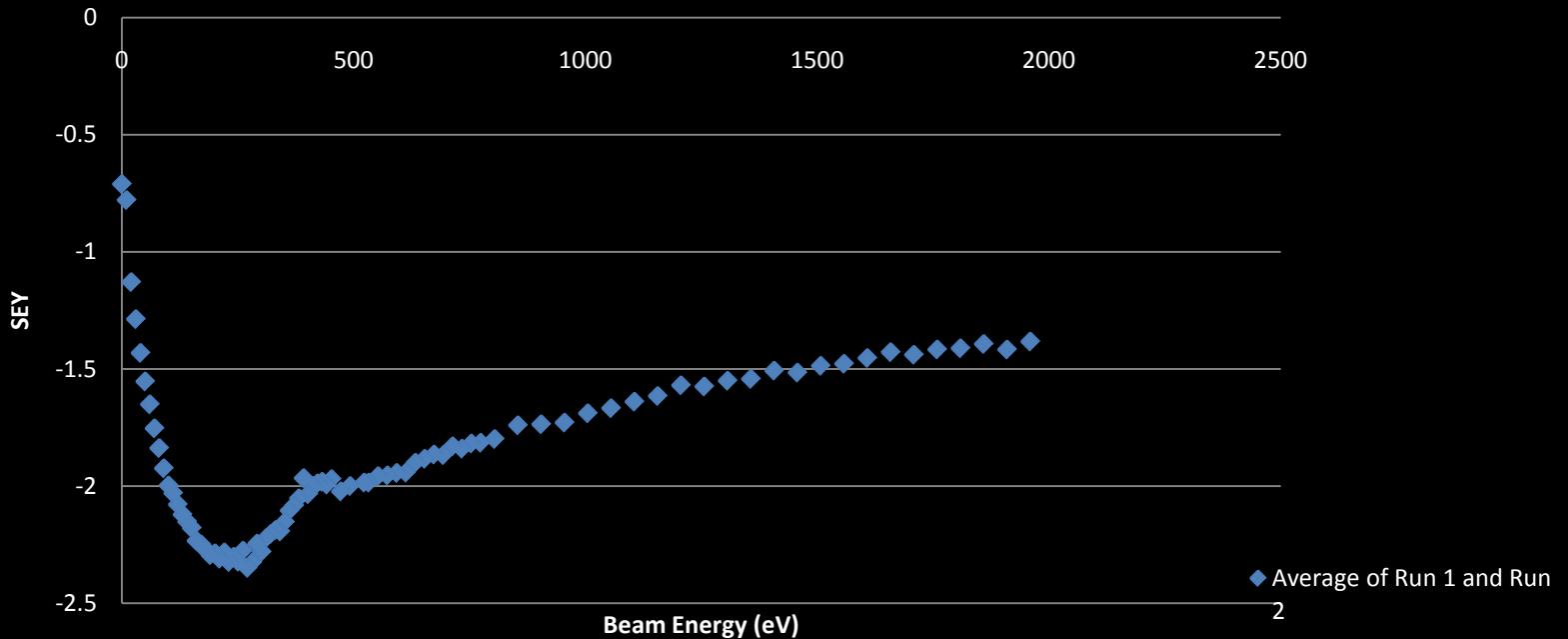
Electron Gun

Mechanical feedthrough for
aperture



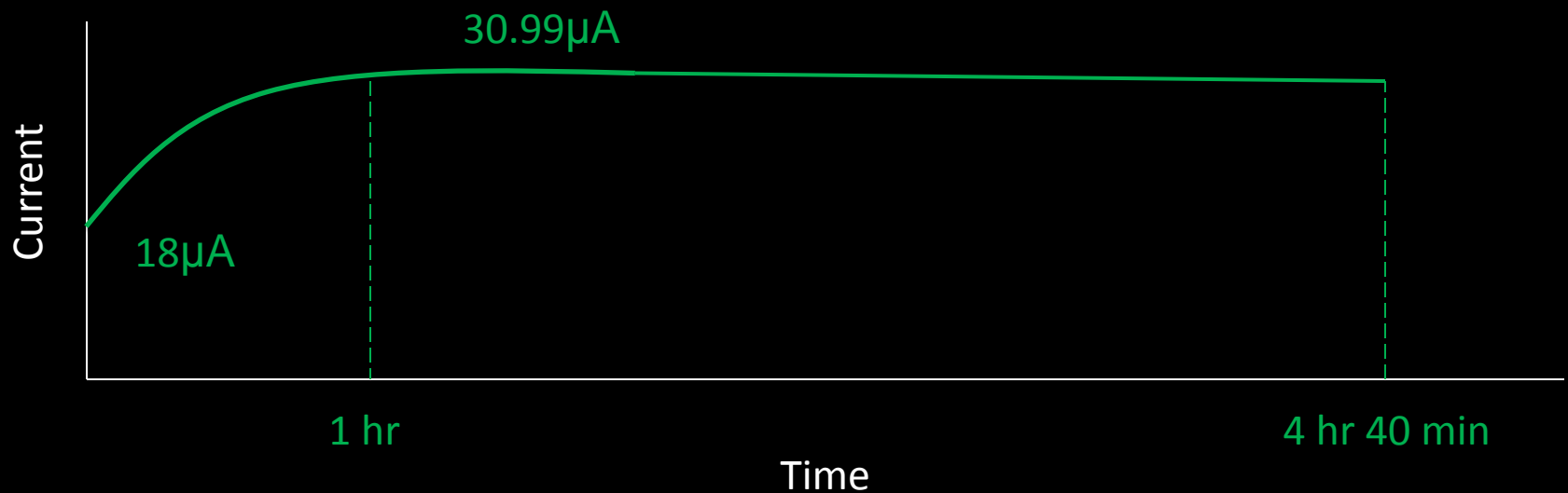
Initial Results

SEY as a Function of Beam Energy
(new copper sample; beam current < 50 nA)



Conditioning

- Made a critical mistake; first hour of conditioning the emission current indicated on the EGPS increased



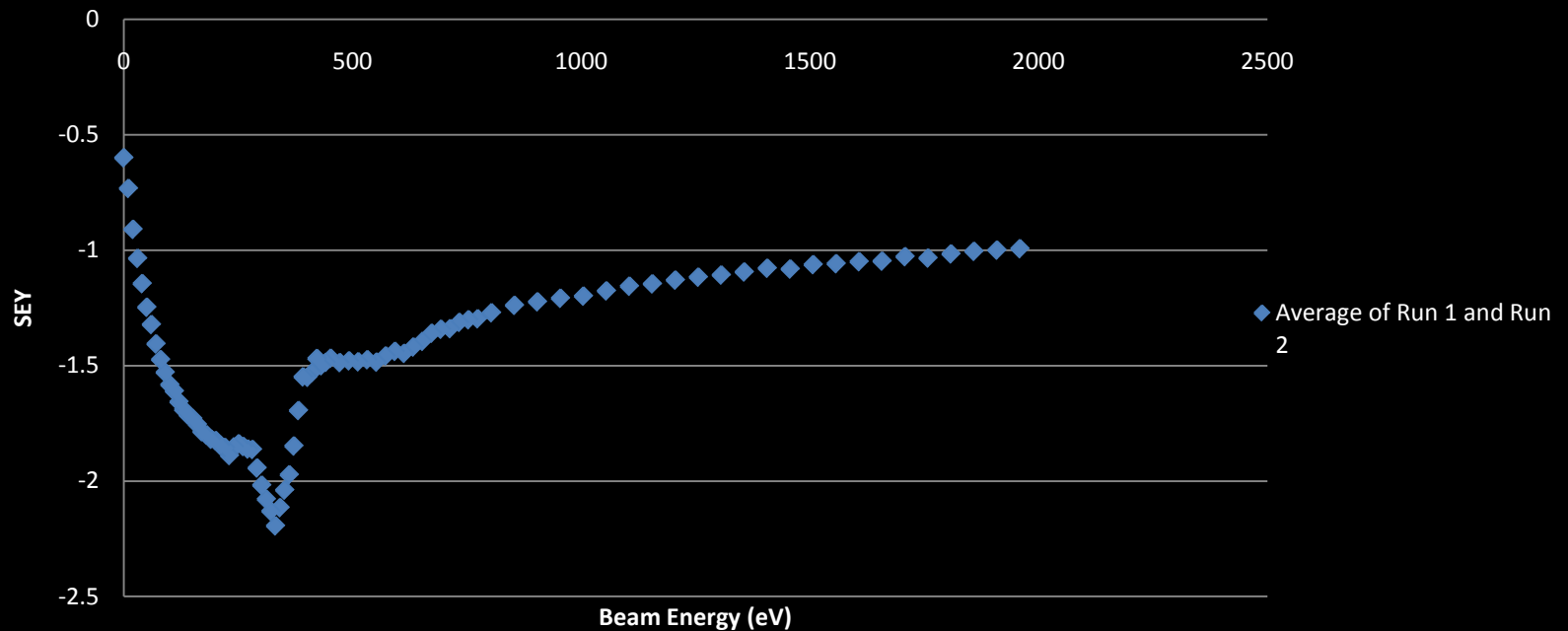
- Estimated dose: $\sim 137.63 \mu\text{A-hr}^*$

Questions About Conditioning (Future Work)

- How does the conditioning beam energy effect sample conditioning?
 - Produce SEY comparisons of conditioned and unconditioned samples for several different conditioning energies
- How does sample bias effect conditioning?
 - Conditioning current measured from EGPS “emission current”, which does not always match actual beam current
 - Can the sample be effectively conditioned with a large positive bias (allowing more accurate dose measurements)?

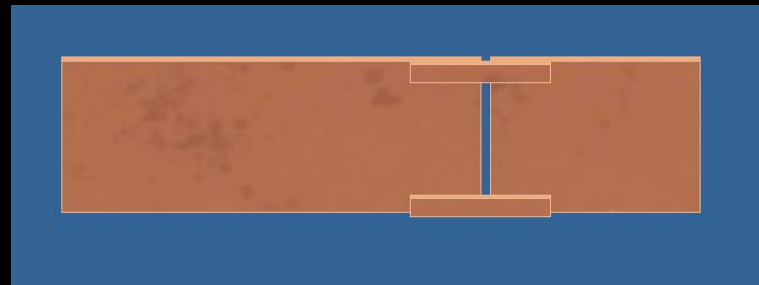
Results After Conditioning

SEY as a Function of Beam Energy
(conditioned copper sample; beam current < 70 nA)

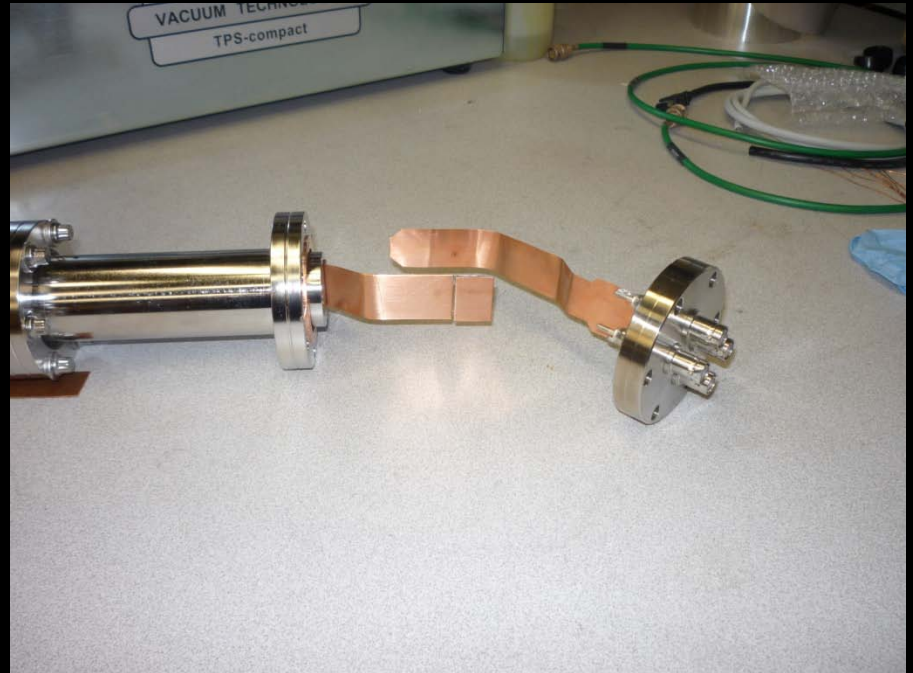
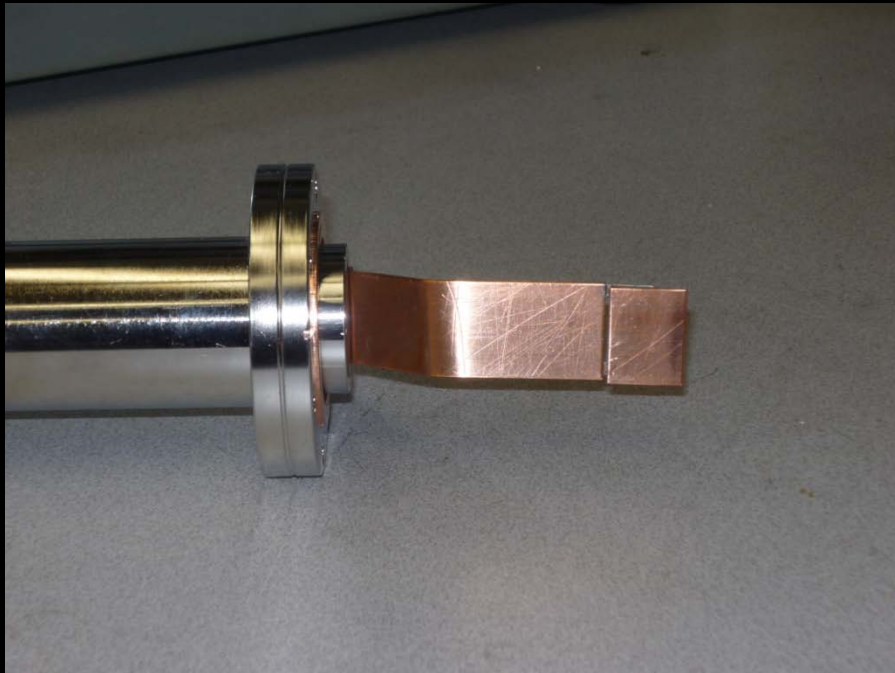


Investigate Spot Size

- Installed an aperture
- Measurement technique:
 - Feed aperture into beam; record position when beam current is reduced to 99% of the unobstructed beam current
 - Continue feeding until beam current drops to 1% of unobstructed beam current and record position
- Double edge aperture used to gain a rough beam profile
 - Raster aperture back and forth, recording the current as a function of position



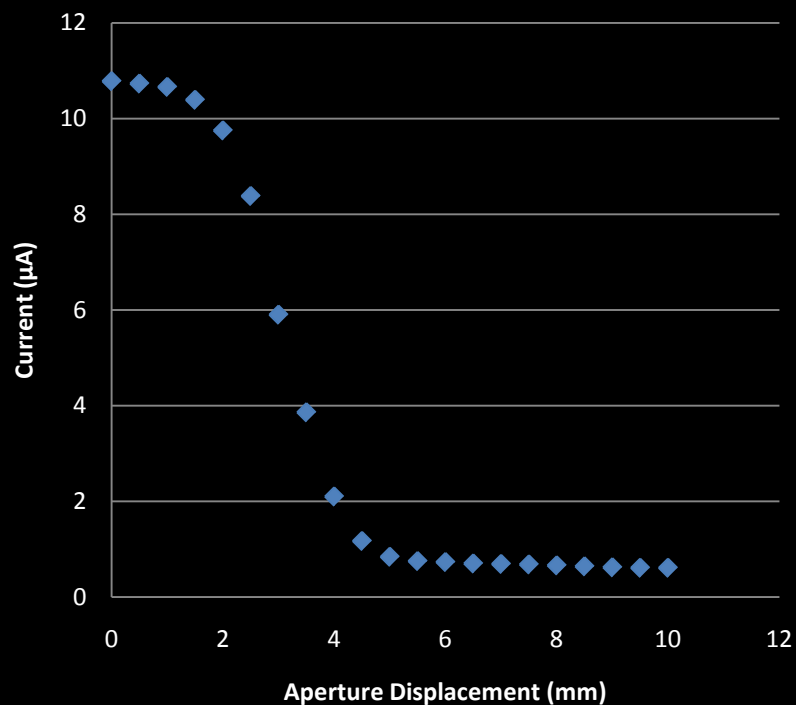
Spot Size Measurements



Spot Size

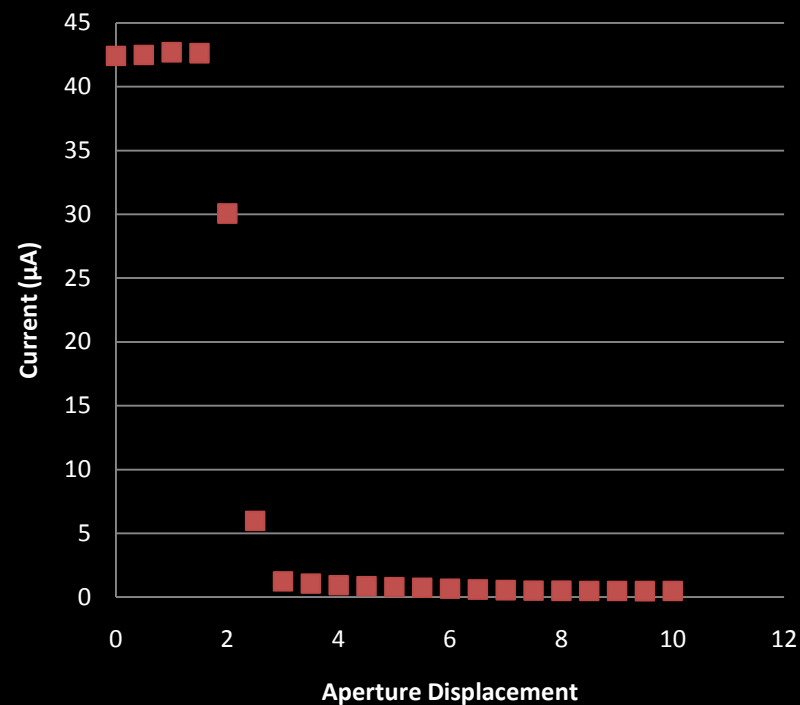
Good Measurements

1000 eV Beam



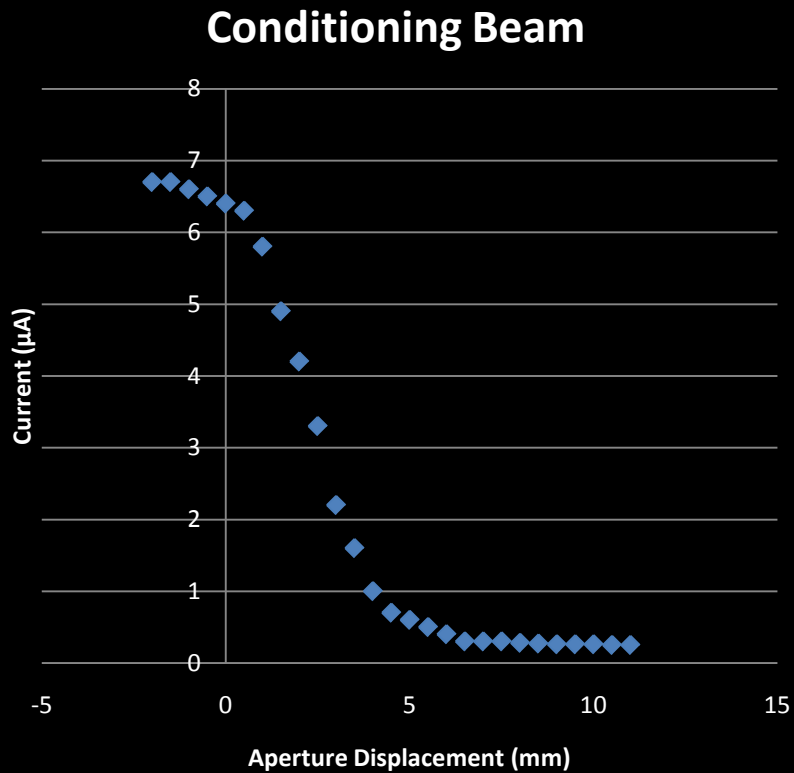
Bad Measurements

400 eV Beam

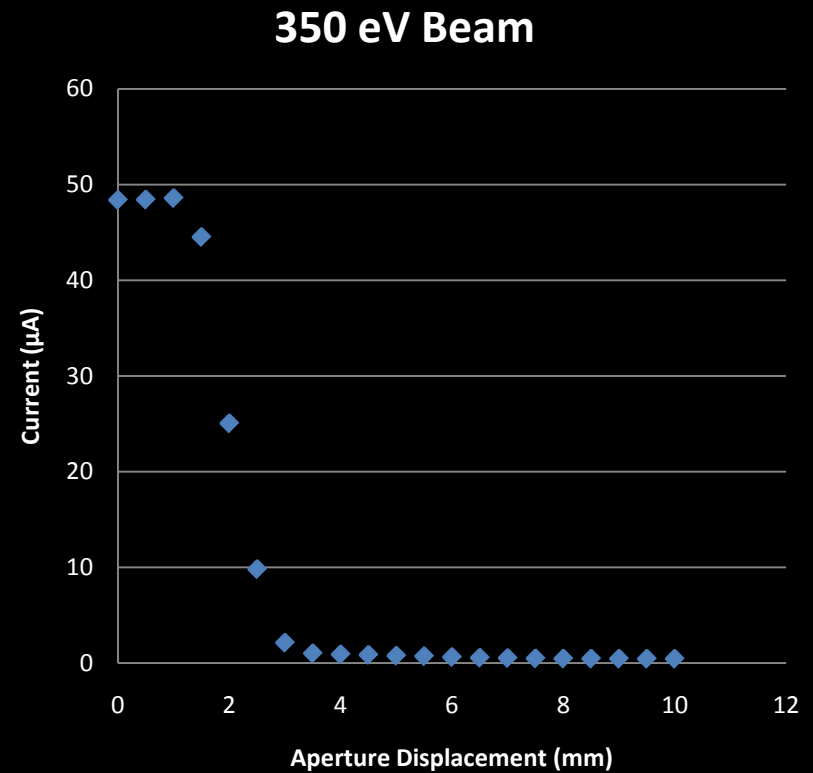


Spot Size

Conditioning Beam



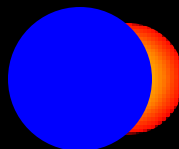
Bad Measurements



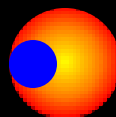
What's Going On?

Three Cases

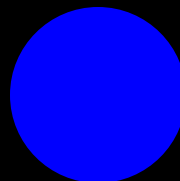
- ~ 400 eV to 200 eV range
=> artificially high SEY
from overlap condition



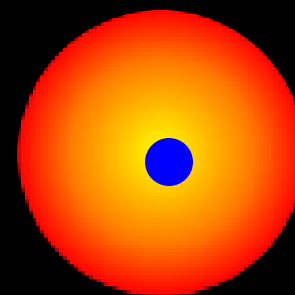
- ~600 eV to 400 eV range
=> appears as a plateau



- ~2000 eV to 600 eV range
=> qualitatively looks fine
but still suffering from
slight overlap



Ideal Case



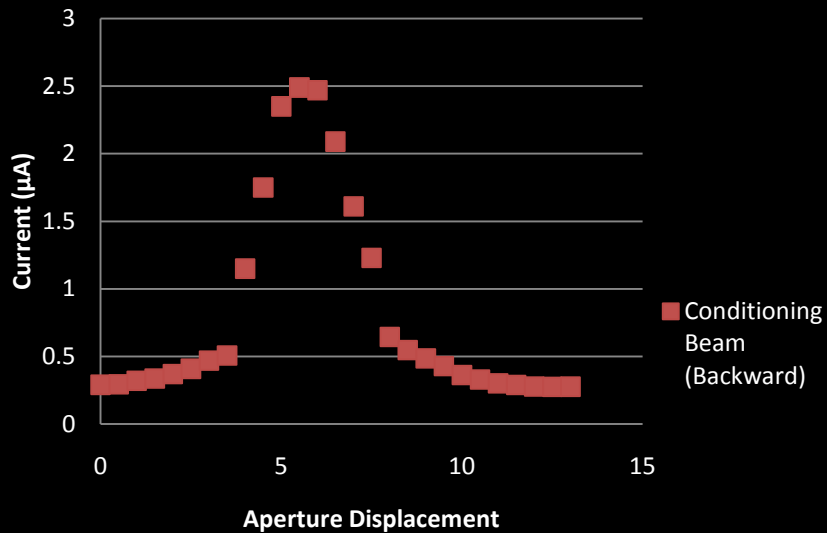
New Parameters

Conditioning Beam:

Energy	500 eV
Focus	100 V
Grid	1 V
1 st Anode	100.1 V
SOURCE	
Voltage	1.6 V
Current	1.622 A
Emission	30.99 μ A

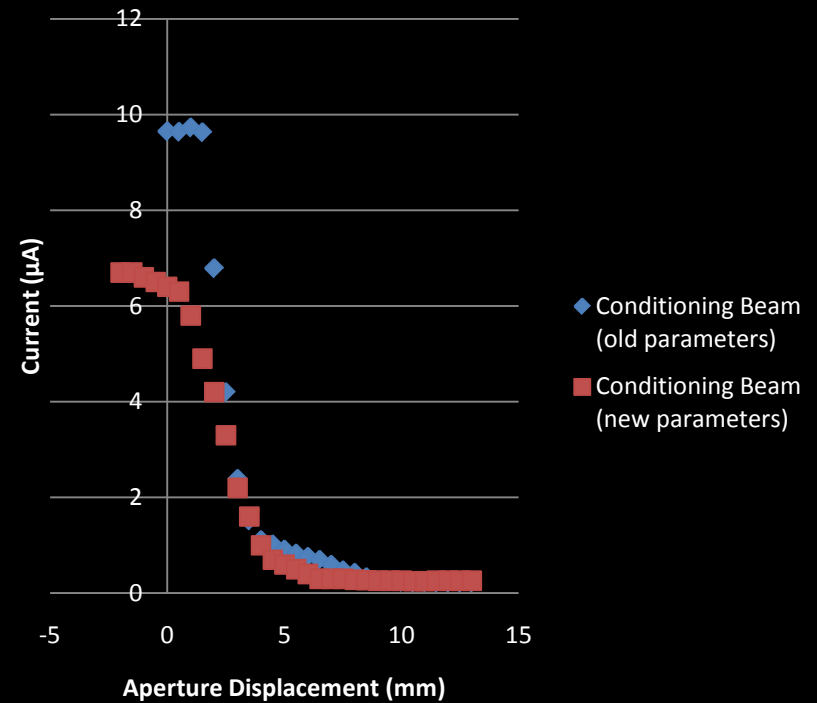
Double Sided Aperture Measurement

Conditioning Beam
Measured with double sided
aperture

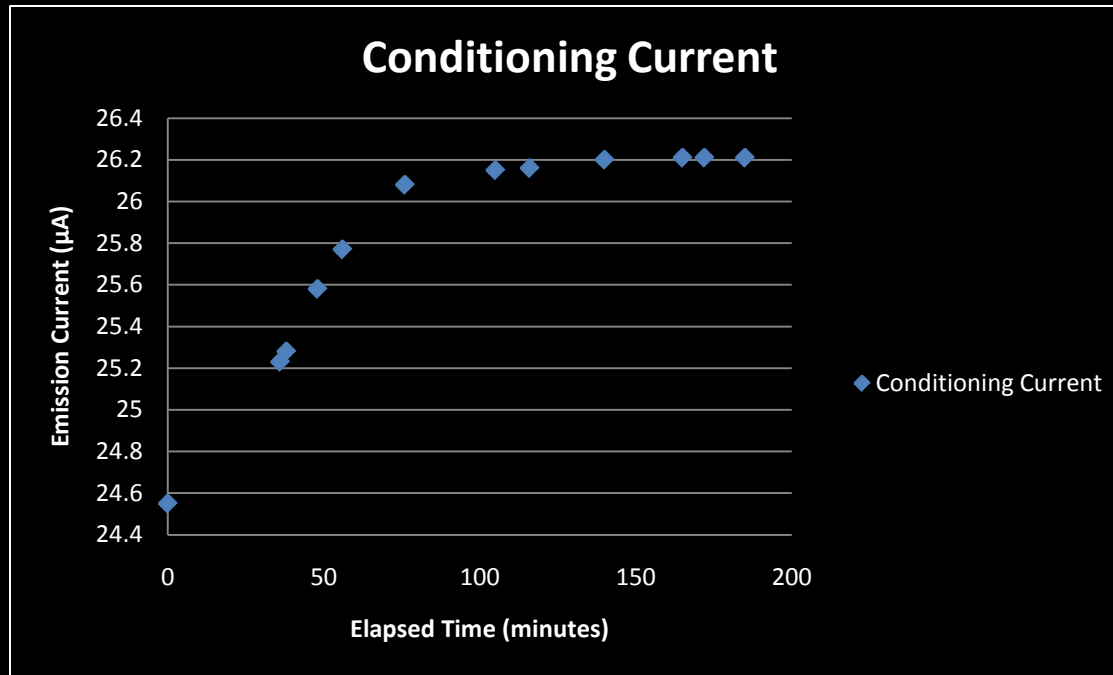


Single Sided Aperture Comparison

Conditioning Beam Comparison

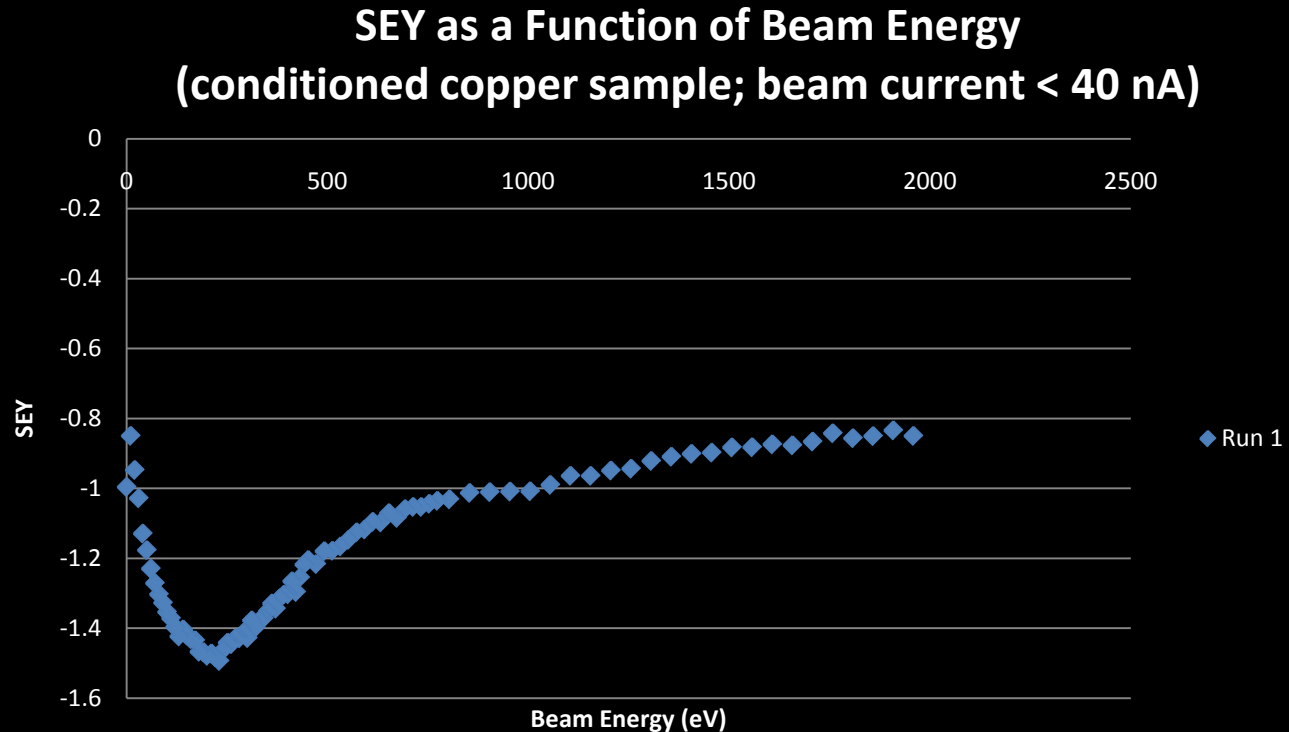


Conditioning Current



Dose approximately 0.041 C/cm²

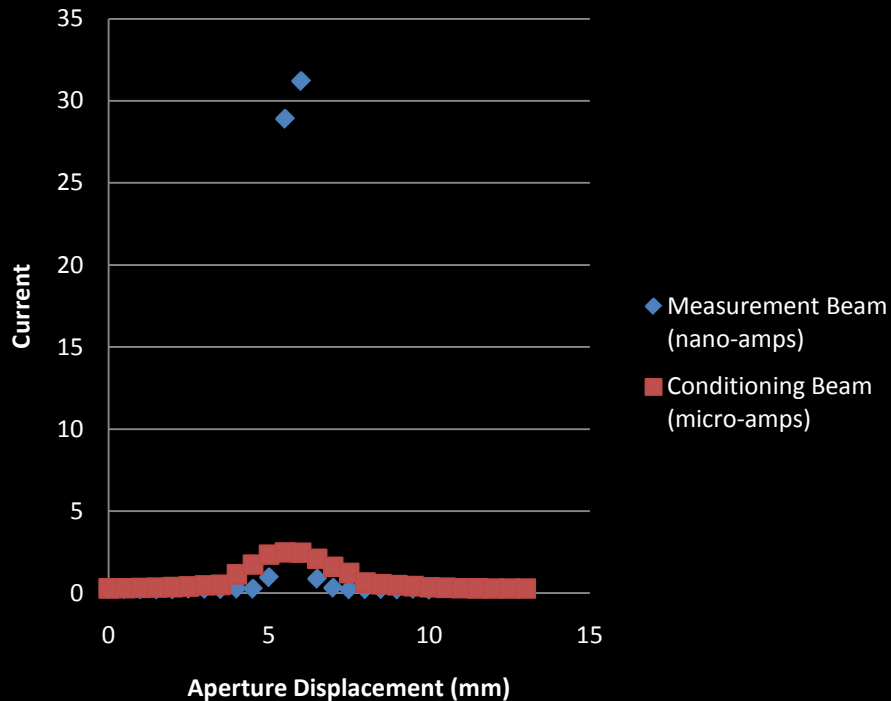
Initial Results with new Parameters



Useful Comparison

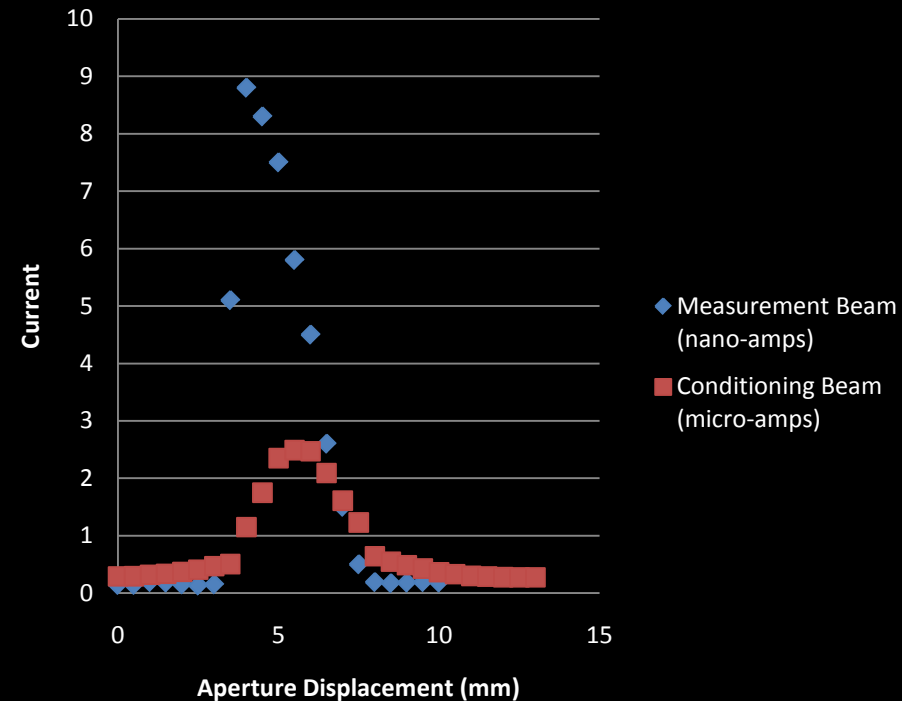
•New conditioning beam and new measurement beam (E=150 eV and F = 310 V in this example)

Spot Size Comparison



New conditioning beam and old measurement beam (E=150 eV and F = 150 V in this example)

Spot Size Comparison



CONCLUSION

- Successful proof of technique
 - Setup for biasing the sample is robust and easily controlled, either manually or via computer
 - Low noise
 - Reasonable results
- Need to develop a solid set of gun parameters for future measurements
 - Raster the beam for a larger, more uniform conditioning?
- Future work should also include a formal study of conditioning

Acknowledgements

- Many thanks to Bob Zwaska for his continued encouragement and support
- Thanks also to Eric Prebys and Carol Angarola along with the entire Lee Teng selection committee for this opportunity